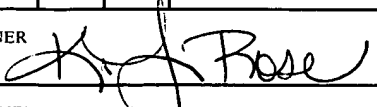


#9

Form PTO-159		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1299		SERIAL NO. 09/428,125		
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Vishnu K. Agarwal et al.				
				FILING DATE October 26, 1999		GROUP 2822		
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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
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							Yes	No
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	AS							
	AT							
EXAMINER				DATE CONSIDERED				
				1/8/03				
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